

Attorney Docket No.: SSI-040

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In	re	App	lication	of:
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William Dale Jones

Serial No.: 10/680,783

Filed: October 6, 2003

For: HIGH-PRESSURE PROCESSING

CHAMBER FOR A

SEMICONDUCTOR WAFER

MS: Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313

Sir:

) Group Art Unit: 1765
) Examiner:
) TRANSMITTAL LETTER
)

162 N. Wolfe Road Sunnyvale, CA 94086 (408) 530-9700

Customer No.: 28960

Enclosed please find a Supplemental Information Disclosure Statement, and Form PTO-1449, including copies of the references contained thereon, for filing in the U.S. Patent and Trademark Office.

A \$180.00 check is also enclosed pursuant to 37 C.F.R. § 1.17(p) for filing this Information Disclosure Statement after three months as set forth in 37 C.F.R. § 1.97(c).

You will also find enclosed the associated Transmittals, Electronic Information Disclosure Statements, and United States Patent and Trademark Office Acknowledgment Receipts for the electronically filed Information Disclosure Statement (EFS ID #74421) filed on December 16, 2004.

The Commissioner is hereby authorized to charge any additional fee or credit overpayment to our Deposit Account No. <u>08-1275</u>. An originally executed duplicate of this transmittal is enclosed for this purpose.

Respectfully submitted, HAVERSTOCK & OWENS LLP

Dated: 1 - 7 - 05

Thomas B. Haverstock Reg. No.: 32,571

Attorneys for Applicant

CERTIFICATE CHOMALING (37 CFRC 107 M

I hereby contily that this paper (clong with any referred to as being combined or end asset) is being densited with the U.S. Petin Service on the close shown below with sufficient postupers first class mult in an envelope addressed to the: Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450

HAVERSTOCK & OWENS LLP

Attorney Docket No.: SSI-04001

PATENT

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

William Dale Jones

Serial No.: 10/680,783

Filed: October 6, 2003

HIGH-PRESSURE PROCESSING For:

CHAMBER FOR A

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Group Art Unit: 1765 Examiner:

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

162 N. Wolfe Road Sunnyvale, CA 94086 (408) 530-9700

The citations listed below, copies attached, may be material to the examination of the above-identified application, and are therefore submitted in compliance with the duty of disclosure defined in 37 C.F.R. §§ 1.56 and 1.97. The Examiner is requested to make these citations of official record in this application.

United States Patents or Published Patent Applications have been filed electronically (EFS ID #74421). Applicants have become aware of the following printed publication which may be material to the examination of this application:

- Japanese Patent Abstract JP 40 5-283511 A; and
- Japanese Patent Abstract JP 2001-77074.

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Attorney Docket No.: PATENT SSI-04001

This Supplemental Information Disclosure Statement under 37 C.F.R. §§ 1.56 and 1.97 is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that anyone or more of these citations constitutes prior art.

Respectfully submitted,

HAVERSTOCK & OWENS LLP

Dated: 1 - 7-05

Thomas B. Haverstock Reg. No.: 32,571

Attorneys for Applicant

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HAVERSTOCK & OWENS LLP.

Page 1 of 2 Acknowledgement Receipt

UNITED STATES PATENT AND TRADEMARK OFFICE **ACKNOWLEDGEMENT RECEIPT**

Electronic Version 1.1 Stylesheet Version v1.1.1

Title of Invention	HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER				
Submission Type: Application Number: EFS ID:	Information Di 10/680783 74421	sclosure Statement *10/680783*			
Server Response:					
	ISVR1	Submission was successfully submitted - Even if Informational or Warning Messages appear below, please do not resubmit this application			
	ICON1 5859				
	USPTOEFSNotice	The documents provided in this submission were accepted by the USPTO. However, the fees associated with new utility and provisional Electronic Filing System (EFS) submission were not accepted by our automated systems because the USPTO software has not yet been updated for the fee structure and amounts required by the Consolidated Appropriations Act, 2005, Section 801, of Division B. In due course a corrected fee may be assessed due to changes associated with the Appropriations Act. We will charge the amount indicated in your submission. If at least the basic filing fee accompanied a new utility or provisional EFS submission, then no surcharge based on fee deficiency will be applied when any fee deficiency is paid. For assistance with e-filing a patent application, contact the Patent Electronic Business Center: Toll –Free Number: 1866 217–9197			

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First Named Applicant: William Jones

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Stylesheet Version v1.1.0	1.1.0
Title of	HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFE
Invention	

TRANSMITTAL

Transmittal

Title of Invention	HIGH-PRESSURE	HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER
Application Number:	10/680783	*10/680783*

Comments

2003-10-06 Date:

First Named Applicant: William Dale Jones

5859 Confirmation Number:

Attorney Docket Number:

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Submitted by:	Elec. Sign.	Sign. Capacity
rhomas 8. Haverstock	/tbh/	
Registered Number: 32571		Attorney

SSI04001-usidst.xml

Documents being submitted

us-ids

us-ids.dtd us-ids.xsl

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18 Stylesheet Version v18.0

> HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR Title of # WAFER Invention ____

10,680783 Application Number.

10/680783

Confirmation Number: 5859 First Named Applicant: William Jones

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20010050096).pn.

US Patent Documents

Attorney Docket Number:

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

ŀ	init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
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ľ		2	4426358	1984-01-17	Johansson]		
1		3	4574184	1986-03-04	Wolf et al.]		
I		4	5374829	1994-12-20	Sakamoto et al.]		
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ľ		9	6089377	2000-07-18	Shimazu]		
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US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init Cite.No.	Fub. No.	Date	Appl.cant	Kind	Class	Subclass
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Signature						
	Examiner N	ame		Date		=

FORM PTO-1449 (Modified)

U.S. Department of Commerce Patent and Trademark Office

Attorney Docket No.: SSI-04001 Applicants: William Dale Jones

Serial No.: 10/680,783

INFORMATION DISCLOSURE TATEMENT BY APPLICANT

	•	Use Several Sheets	ii Necessary)							
37 CFR § 1.98	B(b))	MADEMA			Filing Date: October 6, 2003 Group Art Unit: 1765					
Т		-		U.S. PATENT DOC	CUMENTS		1			
Examiner Initials		Serial / Patent Number	Issue Date	Applic	cant / Patentee	Class	Subclass	Filing	Date	
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		Document Number	Publication Date	Country	/ Patent Office	Class	Subclass	Trans	slation	
		Number	Fublication Date	Country		Class	Subclass	Yes	No	
	AK	JP 40 5283511 A	10/29/93		JP	H01L	21/68	х		
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	AN									
	AO									
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